



SCE-110 Plasma System



Siemens S7-200 Series "Touch Panel" Control Graphic Operational Display - Pass Word Protected

Inductive Coupling Optional:Quartz Rails and Quartz Rack Ensures multi-directional cleaning or surface modification unmatched by box type systems.

"Ultra Clean" Quartz Chamber

There are no metal parts inside this chamber, your parts aren't exposed to the particulates associated with metal chambers.

Immersing parts in low temperature plasma may be your final cleaning solution !!

Anatech's plasma systems are CFC and effluent free, operator and environmentally safe, easily operated.

Home Page: www.anatechusa.com Email : info@anatechusa.com

SCE-110 Barrel Plasma System

Control System:

Siemens S7-200 Programmable Logic Controller LCD Display:

> Pressure display Gas flow with mass flow controllers (2) Single gas input Process time remaining

Control System:

Options:

3rd Gas channel Data logging Capacitance manometer Temperature sensor Throttle valve Nitrogen backfill Slow pump and particle reduction Operational Light Array

Reactor Chamber:

Quartz chamber 10" Diameter x 18" Long Front Loading Viewport on front door with UV shield

Options:

Quartz rails & shelves (up to 3) Planar electrode

RF Power Source:

0-600 Watt, 13.56 MHz Forward and reflected power reading Automatic Matching Network

Options:

1000 Watt 13.56 MHz supply

Power Requirements:

115 VAC 15A 50/60 HZ

Options:

220 VAC

Dimensions:

System comes in a standard 19 inch half rack

36 inch high x 23 inch wide x 27 inch deep

250 lbs Crated weight (estimated)

Vacuum System:

23 CFM Standard Main Vacuum Valve system controlled 6 feet of 1.500 " ID Vacuum line Oxygen Service, Class "B" Preparation

Vacuum System:

Options:

Corrosive service Mist eliminator Oil filtration

CALL ANATECH USA TO DISCUSS YOUR APPLICATION

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